Electronic Supplementary Information for:

Solution-based *in-situ* deposition of Sb₂S₃ from a single source precursor for resistive random-access memory devices

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Figure S1. FT-IR spectrum of the $[Et_3NH]^+$ $[(OC_3H_7)_2S_2P]^-$ ligand using KBr discs



Figure S2. Room temperature {¹H} NMR spectrum of $[Et_3NH]^+$ $[(OC_3H_7)_2S_2P]^-$ ligand (in CDCl₃).



Figure S3. Room temperature ³¹P{¹H} NMR spectrum of $[Et_3NH]^+$ $[(OC_3H_7)_2S_2P]^-$ ligand (in CDCl₃).



Figure S4. FT-IR spectrum of the $Sb[(OC_3H_7)_2S_2P]_3$ complex using KBr discs



Figure S5. Room temperature {¹H} NMR spectrum of $Sb[(OC_3H_7)_2S_2P]_3$ complex (in CDCl₃).



Figure S6. Room temperature ${}^{31}P{}^{1}H$ NMR spectrum of $Sb[(OC_3H_7)_2S_2P]_3$ complex (in CDCl₃).



Figure S7. XRD spectrum of the as-deposited Sb₂S₃ on FTO at various reaction times using $Sb[(OC_3H_7)_2S_2P]_3$ as SSP



Figure S8. a) SEM micrograph b) EDX elemental mapping c) EDX spectrum with percentage of elements of deposited Sb_2S_3 film on FTO at a reaction time of 12hr



Figure S9. a) SEM micrograph b) EDX elemental mapping c) EDX spectrum with percentage of elements of deposited Sb_2S_3 film on FTO at a reaction time of 18hr



Figure S10. Size distribution histogram of $\mathsf{Sb}_2\mathsf{S}_3$



Figure S11. Cross-section image of deposited Sb_2S_3 on FTO



Figure S12. Bipolar non-volatile resistive switching behaviours of the W/Sb₂S₃/FTO